

Fig. 1

Fig. 2A

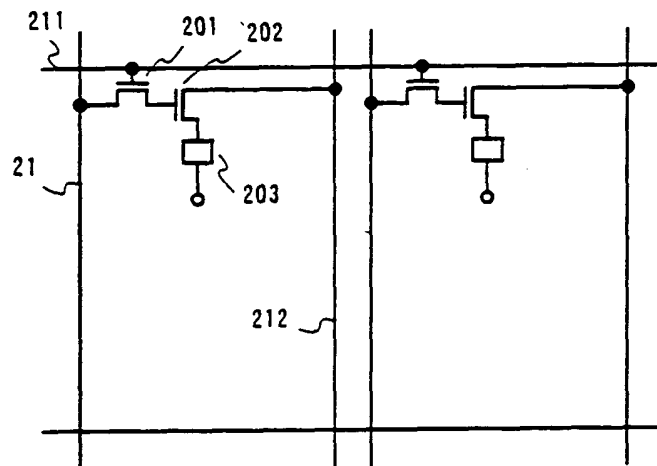
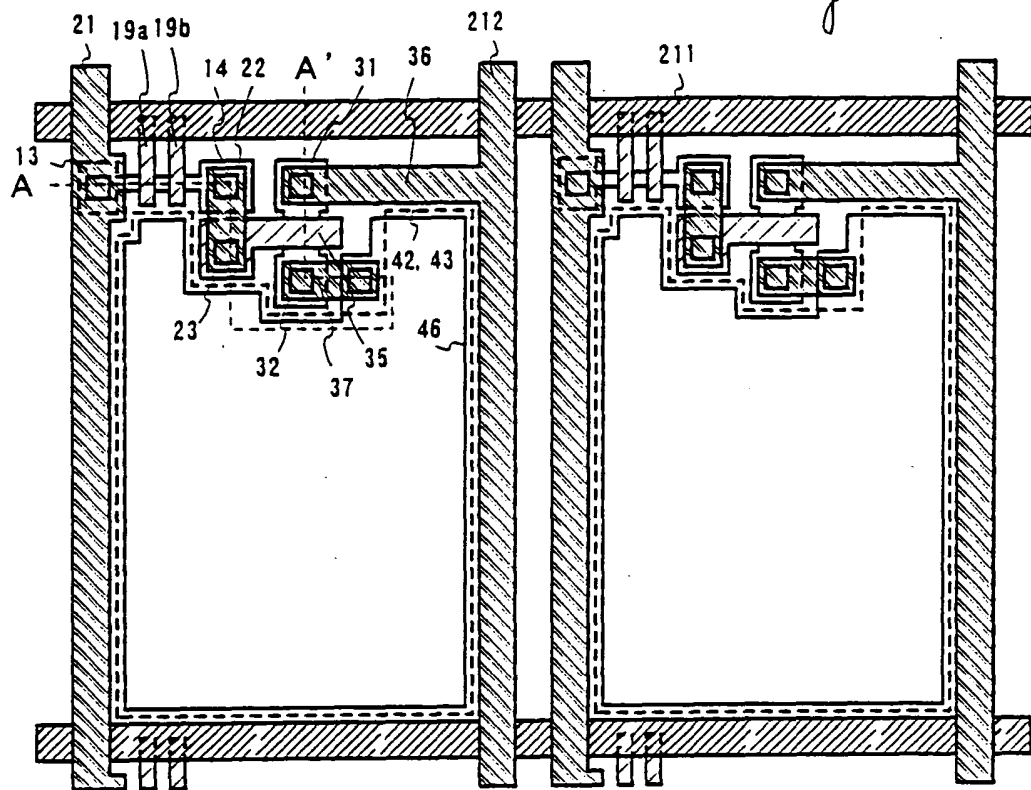


Fig. 2B

Fig. 3A CRYSTALLIZATION STEP

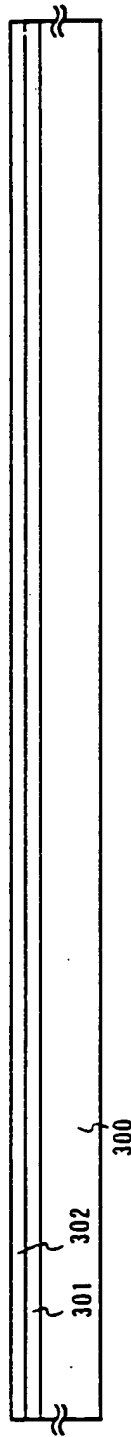


Fig. 3B STEP OF ADDING N-TYPE IMPURITY ELEMENT

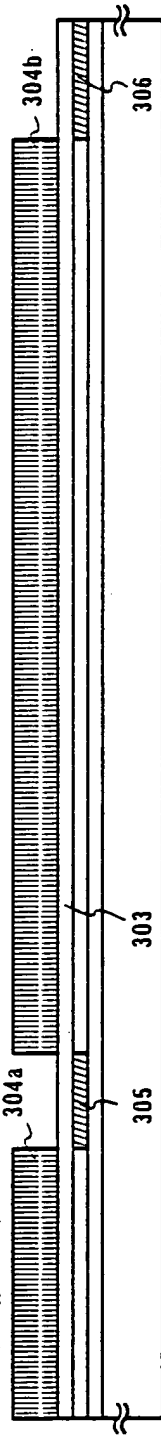


Fig. 3C LASER ANNEALING STEP



Fig. 3D

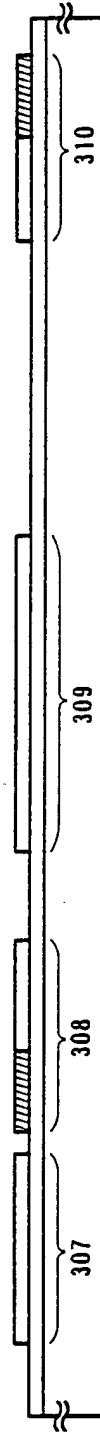
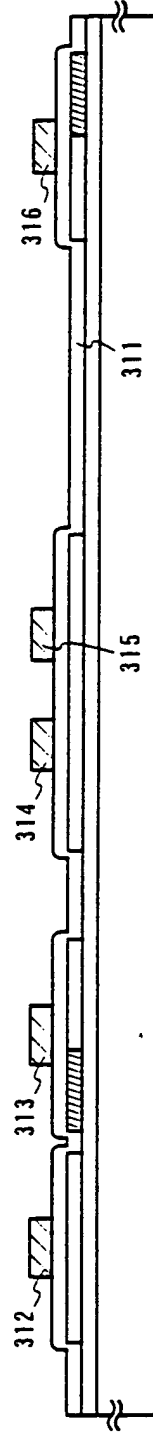


Fig. 3E



STEP OF ADDING N-TYPE IMPURITY ELEMENT

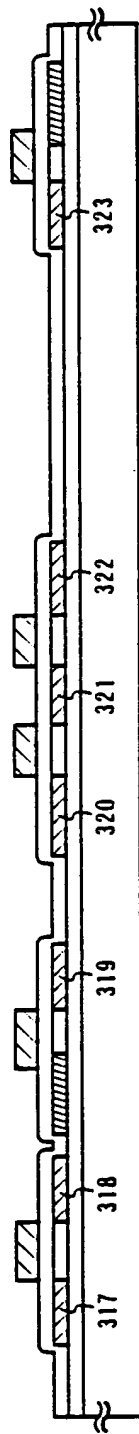


Fig. 4A

STEP OF ADDING N-TYPE IMPURITY ELEMENT

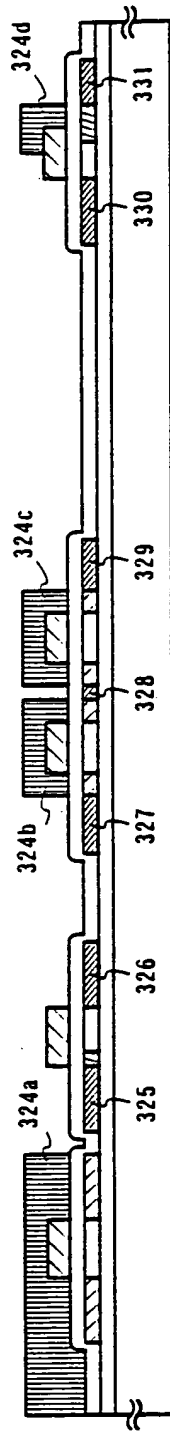


Fig. 4B

STEP OF ADDING P-TYPE IMPURITY ELEMENT

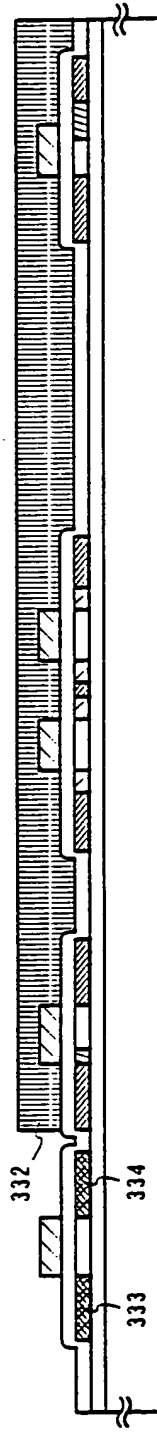


Fig. 4C

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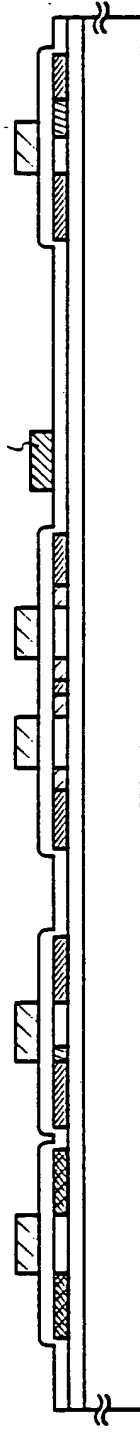


Fig. 4D

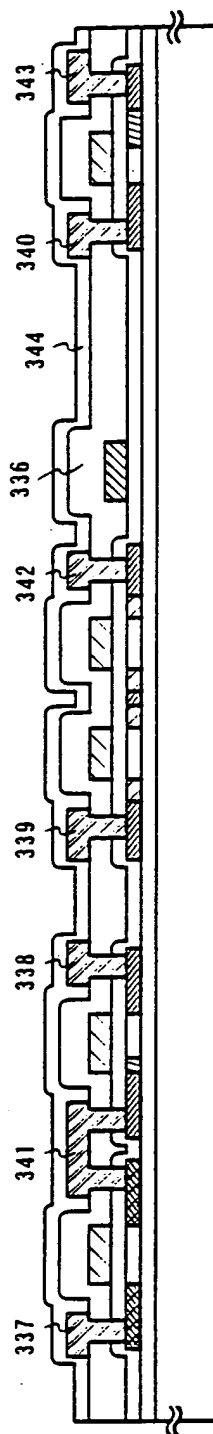


Fig. 5A

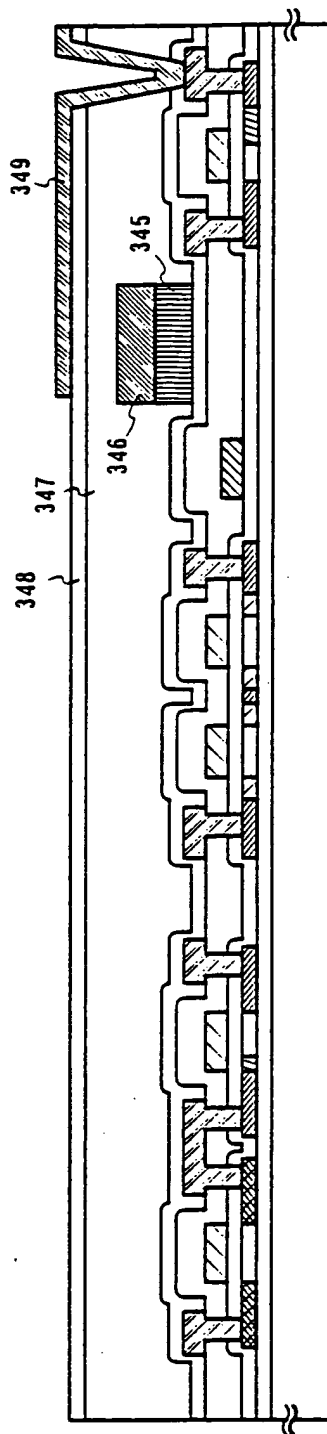


Fig. 5B

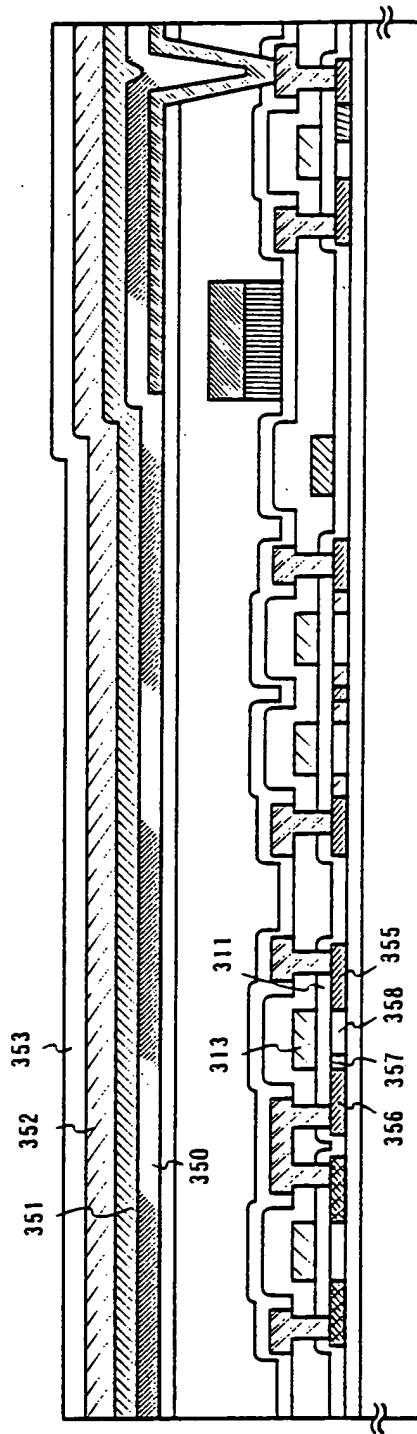


Fig. 5C

P-channel TFT 206
N-channel TFT 205
N-channel TFT 205

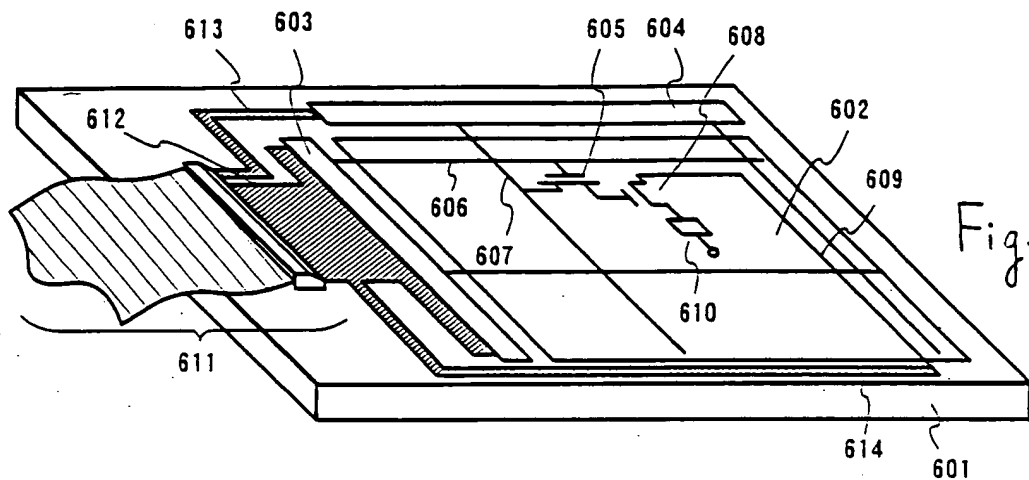


Fig. 6

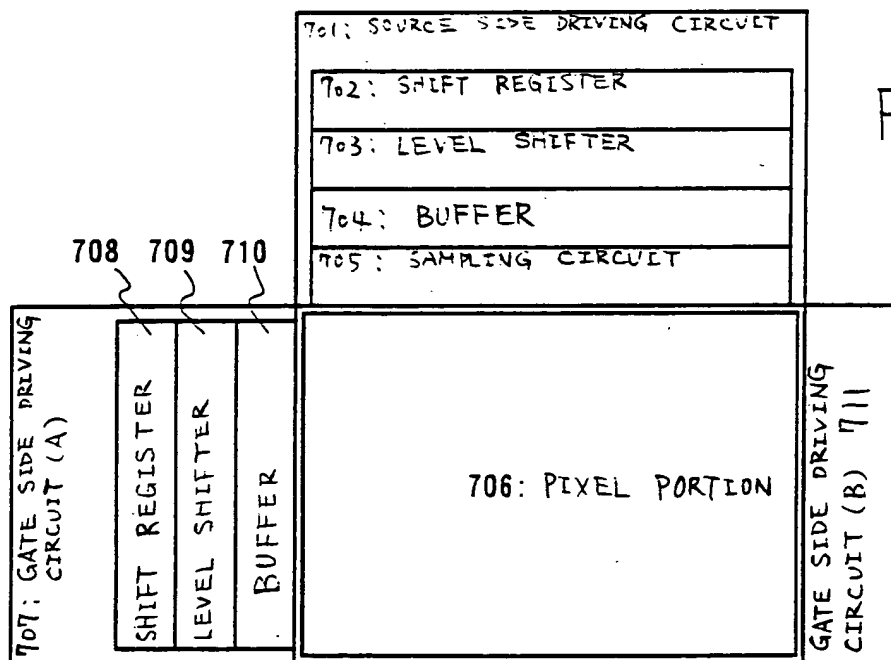


Fig. 7

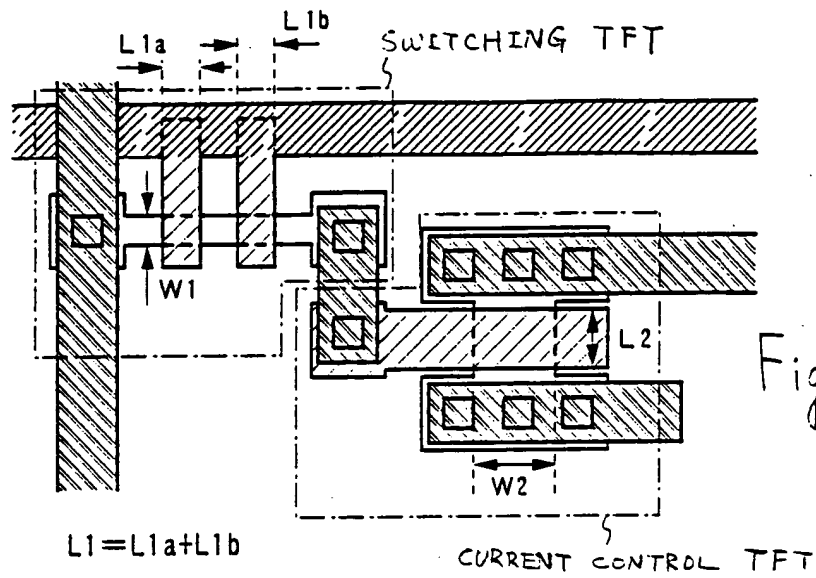


Fig. 8

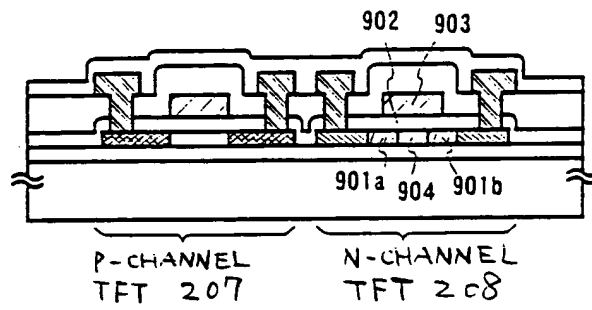


Fig. 9

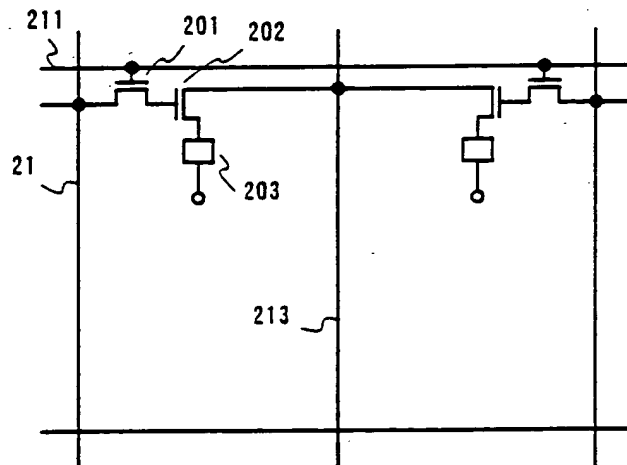


Fig. 10

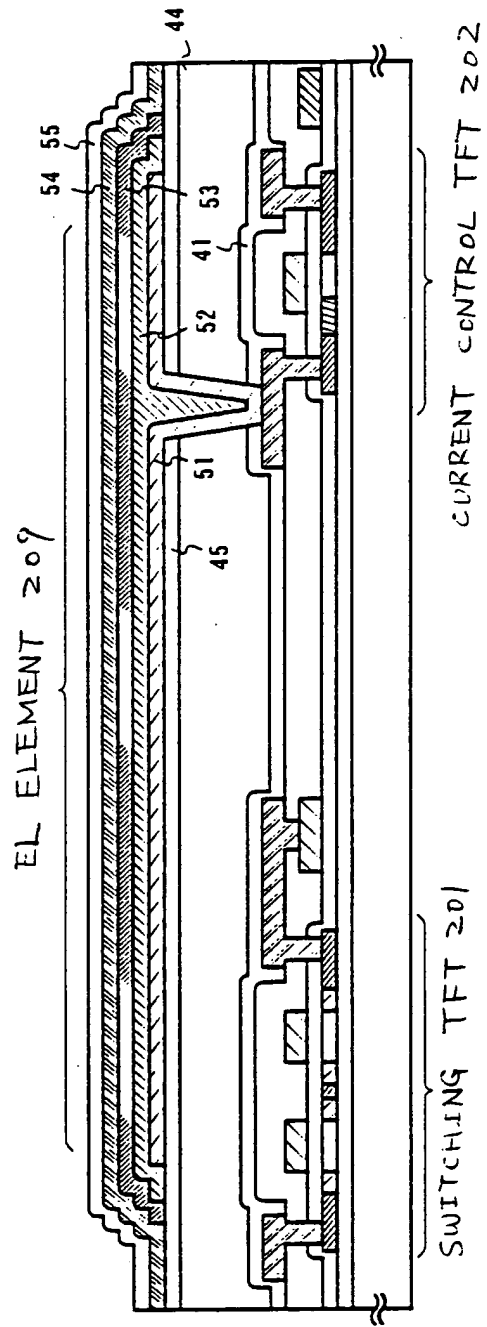


Fig. 11

Fig. 12A

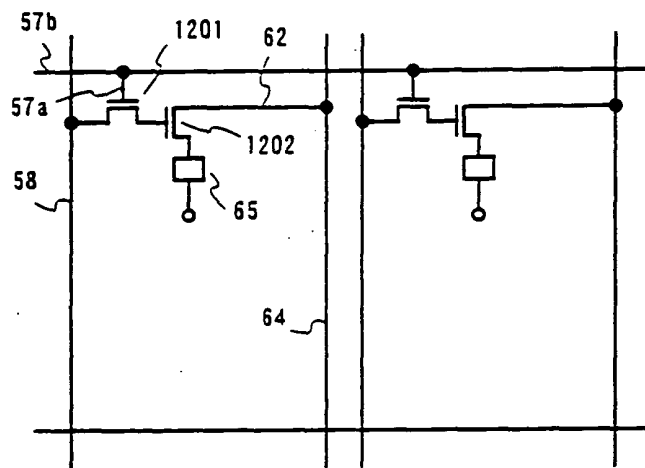
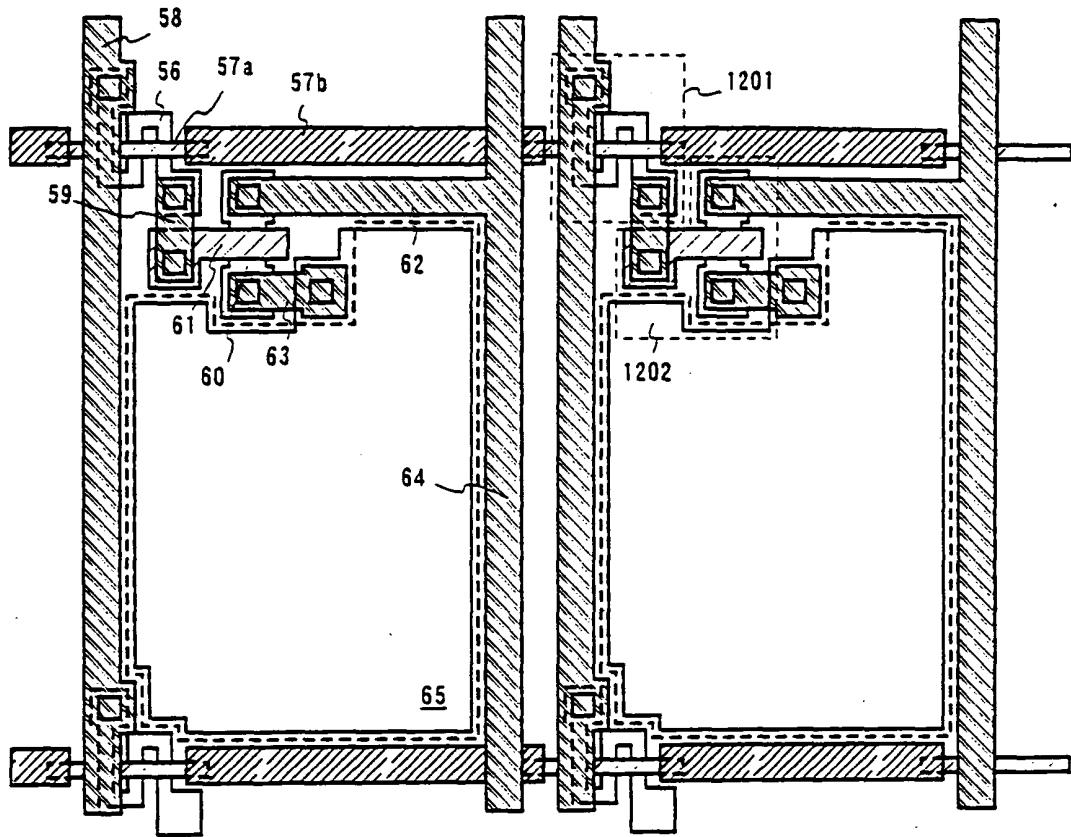


Fig. 12B

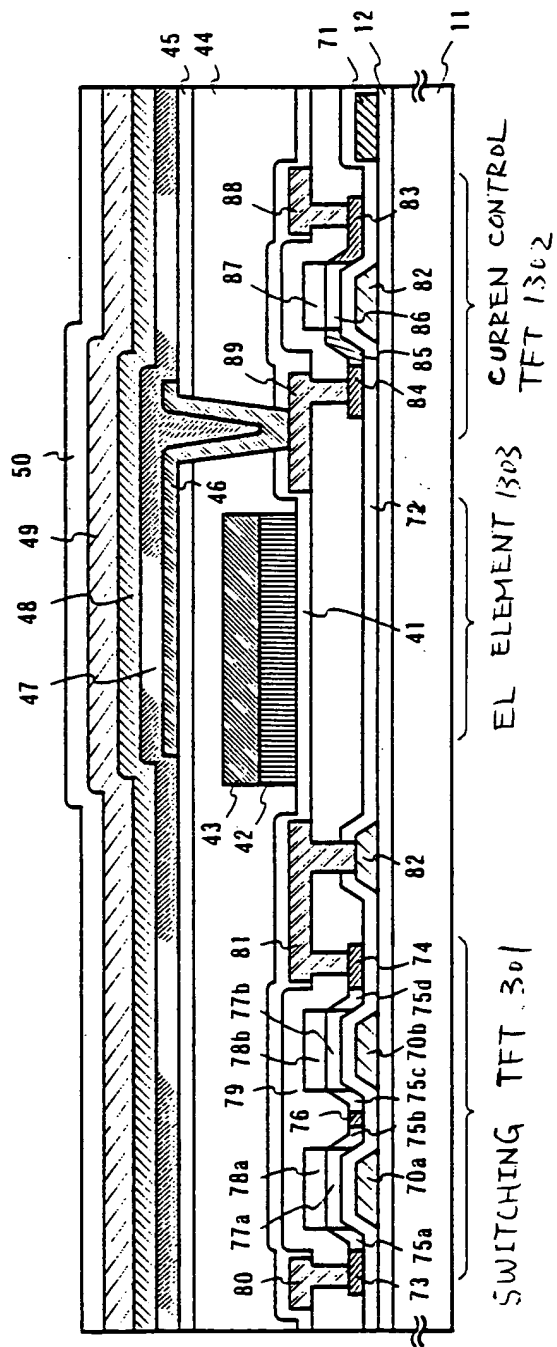


Fig. 13

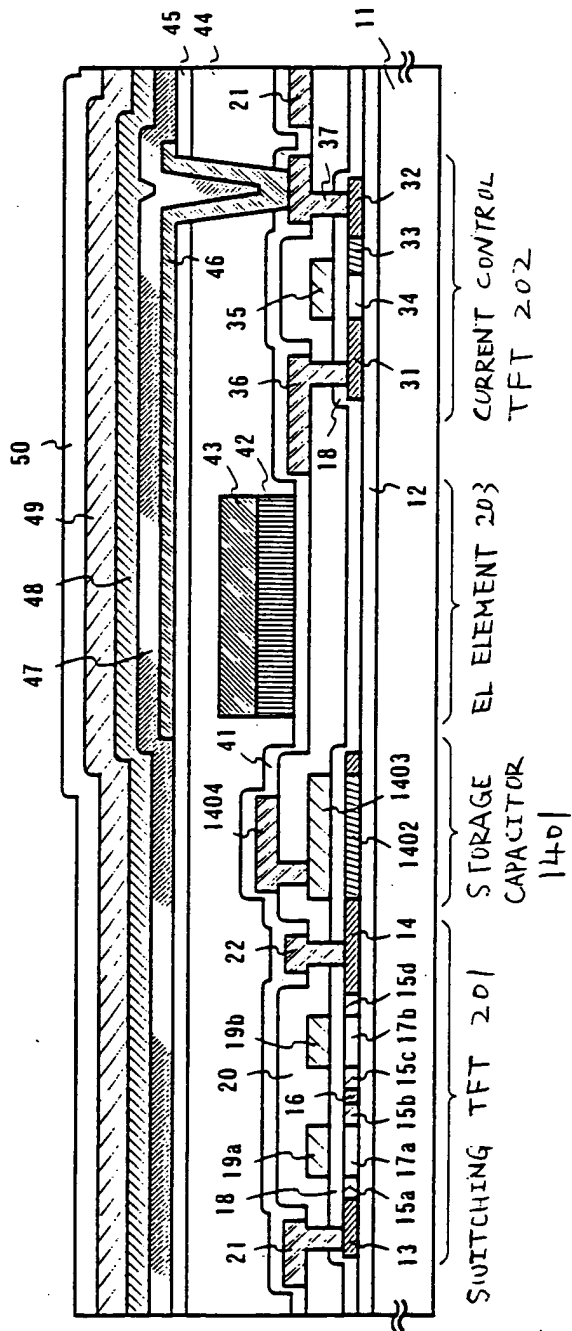


Fig. 14

Fig. 15A

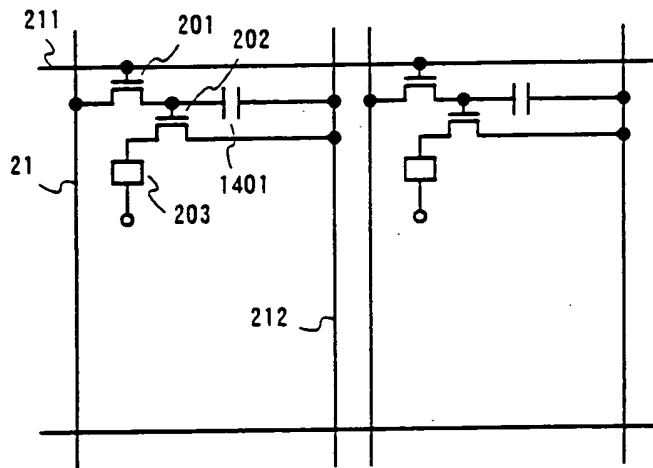
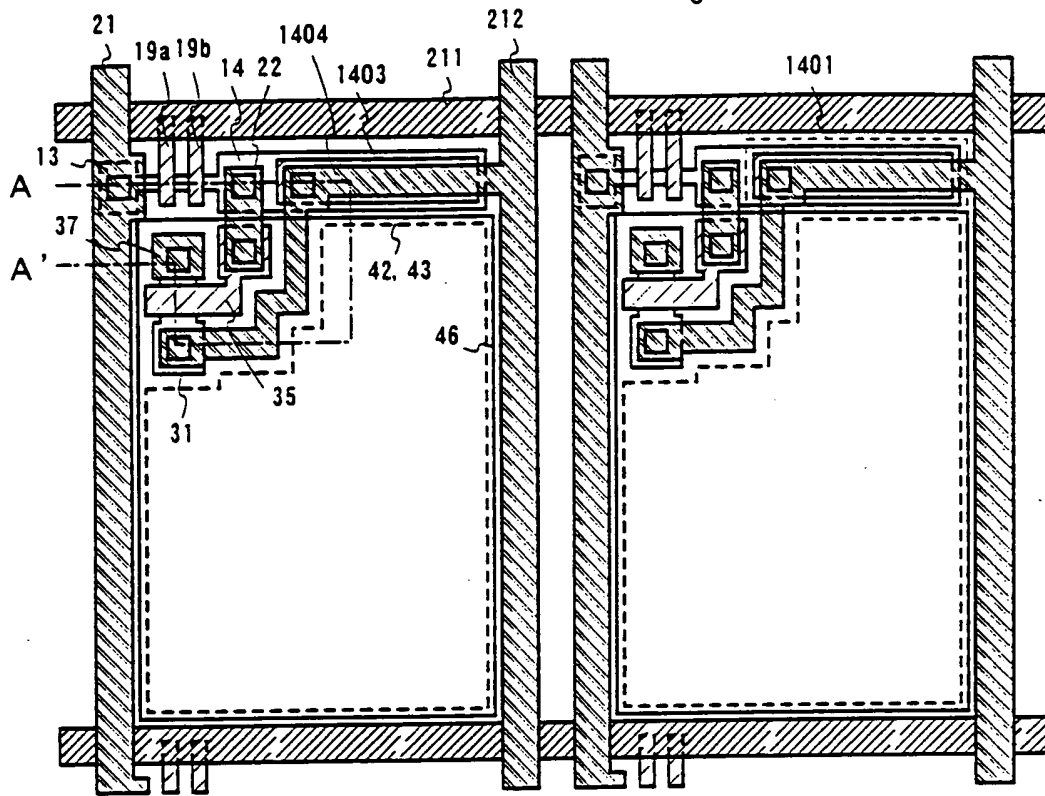
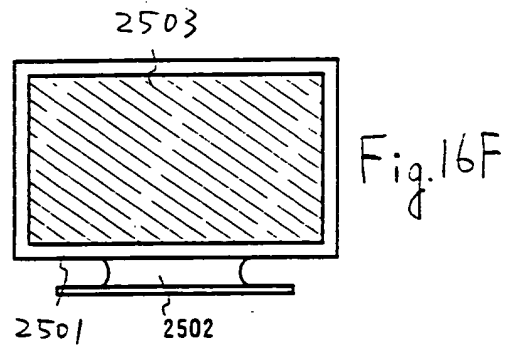
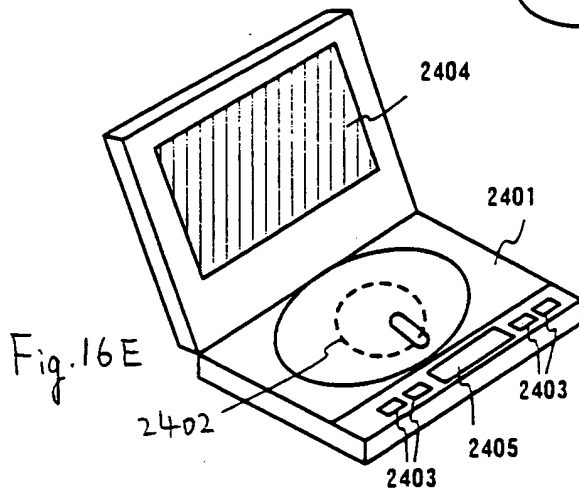
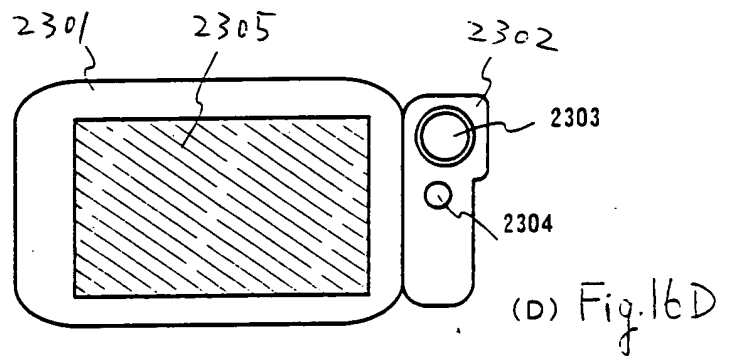
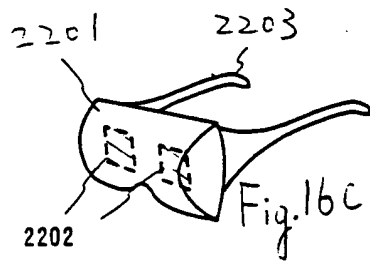
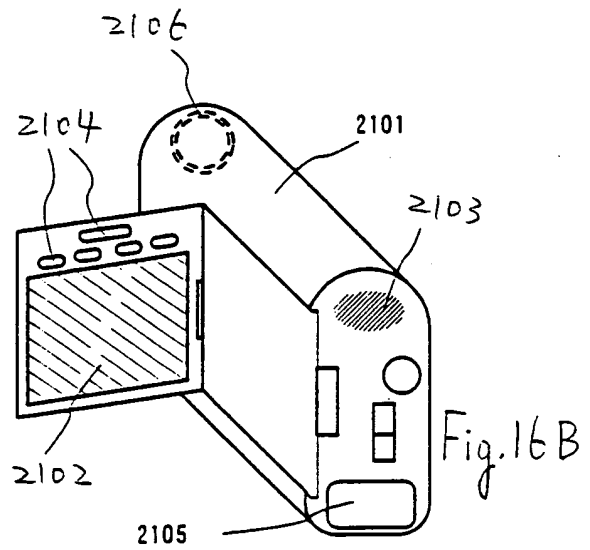
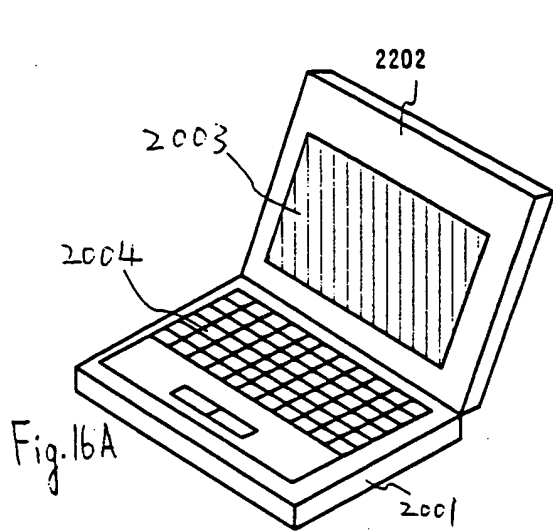


Fig. 15B



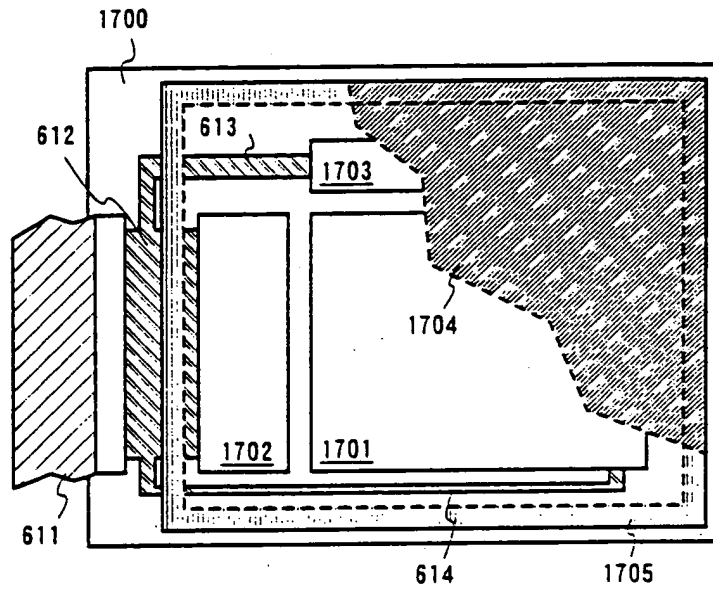


Fig. 17A

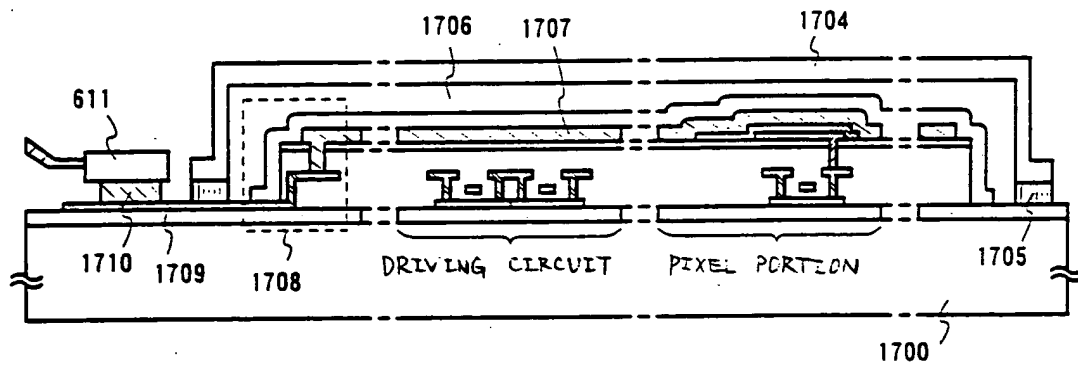


Fig. 17B

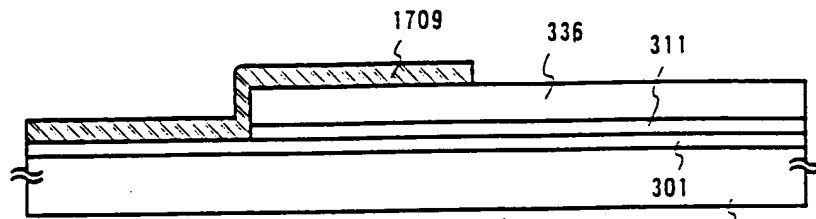


Fig. 18A

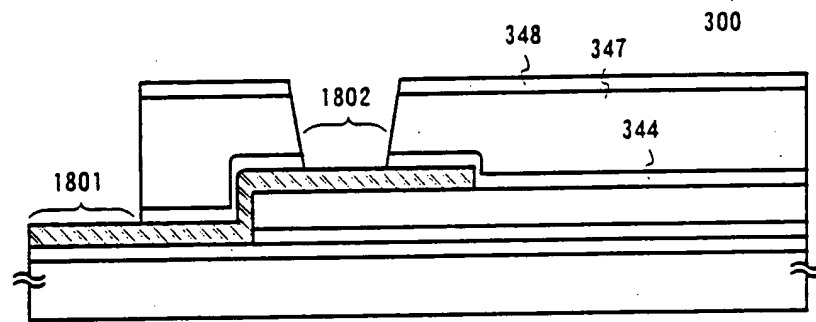


Fig. 18B

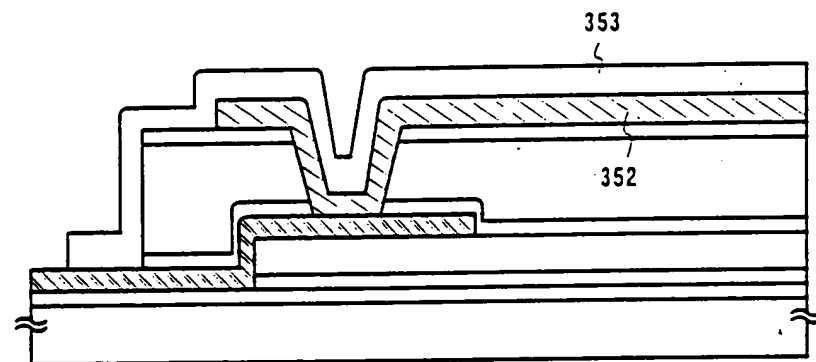


Fig. 18C

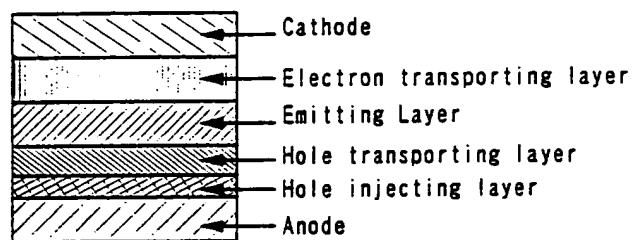


Fig.19

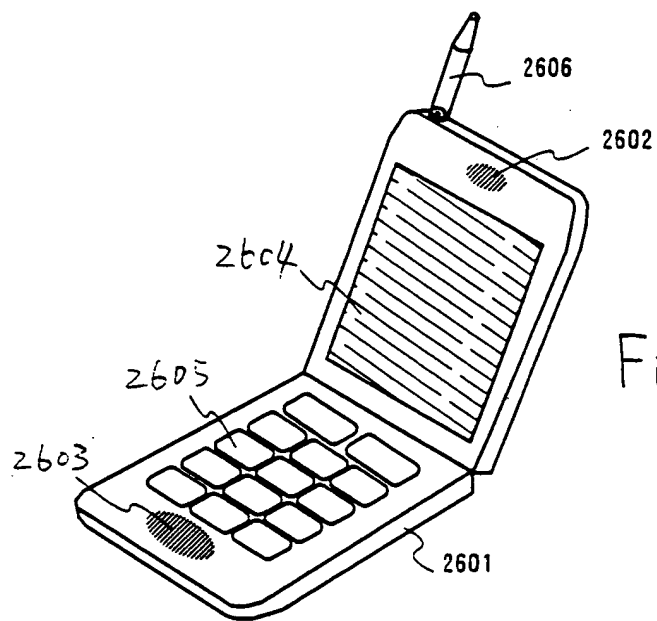


Fig. 20A

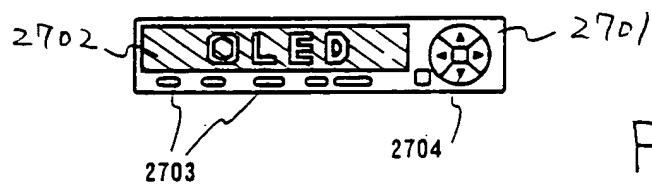


Fig. 20B

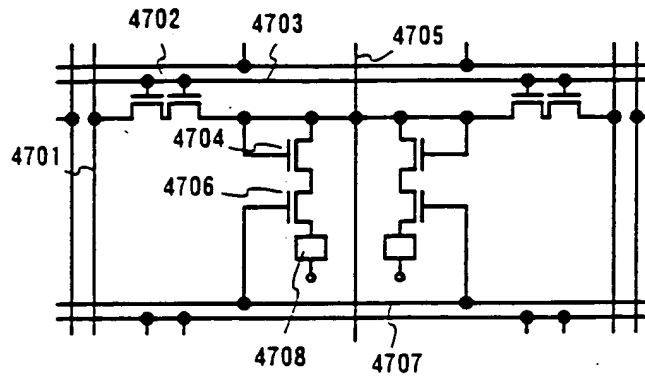


Fig. 21A

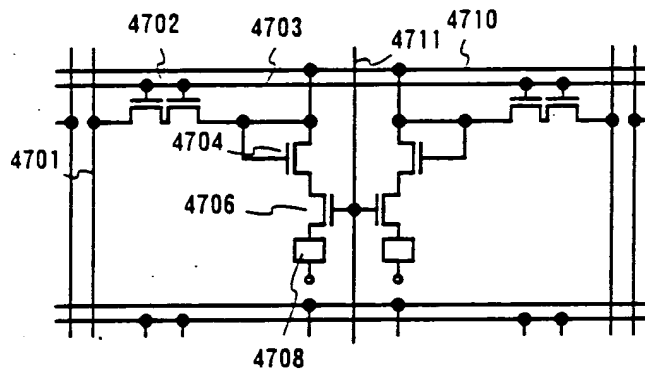


Fig. 21B

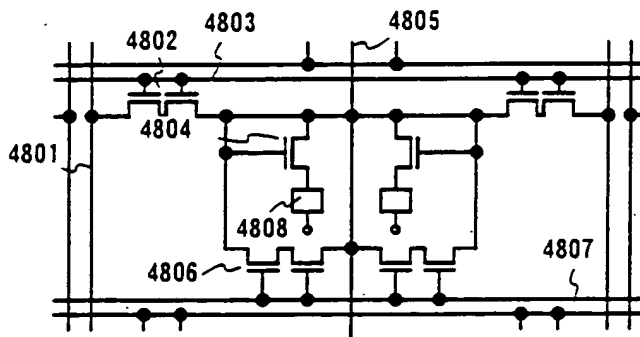


Fig. 22A

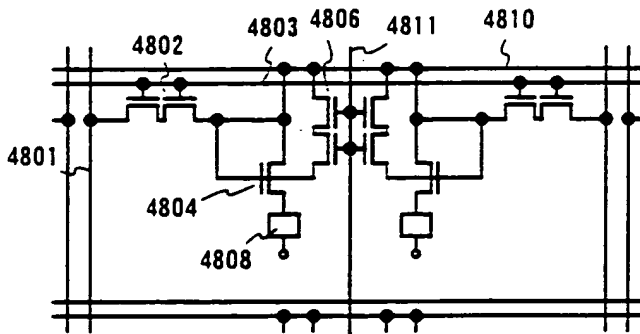


Fig. 22B

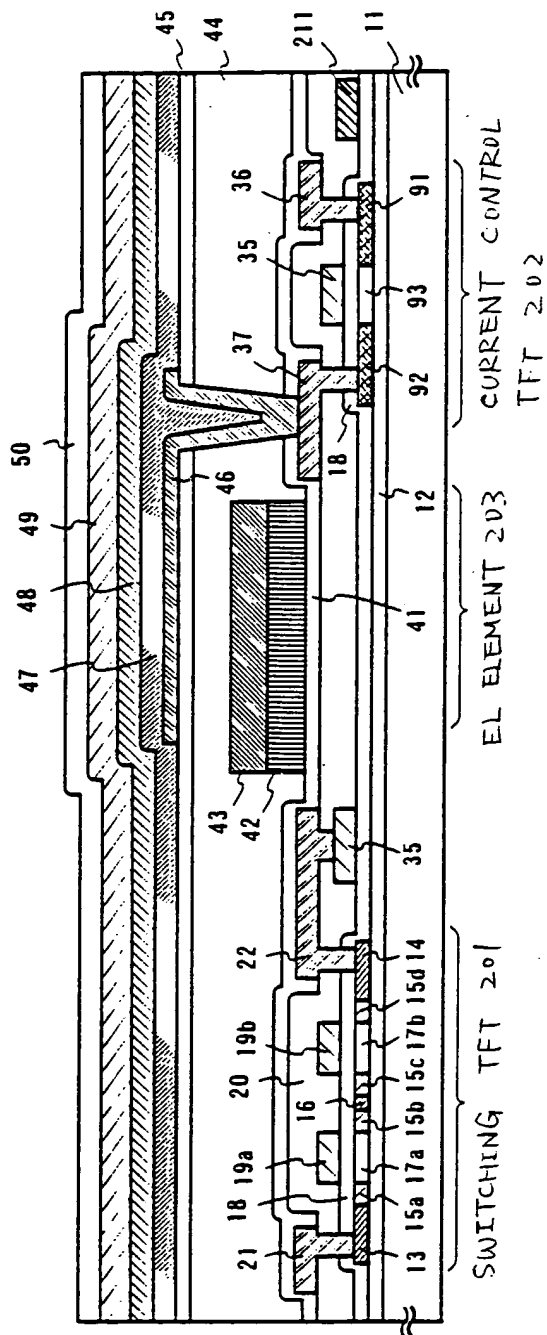


Fig. 23